

Notice of References Cited	Application/Control No. 10/812,092	Applicant(s)/Patent Under Reexamination MIZUTANI ET AL.	
	Examiner Cynthia Hamilton	Art Unit 1752	Page 1 of 1

U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-			
	B	US-			
	C	US-			
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FOREIGN PATENT DOCUMENTS

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NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Flanigan et al, "Surface roughness development during photoresist dissolution," J. Vac. Sci. Technol. B 17 (4), July/Aug 1999, American Vacuum Society, pages 1371-1379.
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*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
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